

Precursor Vapor Delivery Systems

VaporStation®

www.cerestechnologies.com/en/our-products

VaporStation® is an advanced, fully automated vapor delivery system engineered to deliver superior vapor concentration at dynamic flow rates. Designed for both end-users and process tool manufacturers, it offers centralized optimization to reduce total cost of ownership while ensuring exceptional reliability.

By eliminating the need for on-tool bubblers and resident chemicals at the point of use, the **VaporStation®** enhances safety and drives efficiencies.

Why choose **VaporStation®**?

- Safe & centralized precursor delivery
- Lowest total cost of ownership
- Stable vapor concentration at dynamic flow rates
- Highest availability through redundancy solutions
- **VaporStation®** is SEMI compliant

Applications

VaporStation® is an enhanced solution for semiconductor fabs, offering precise and efficient bulk vapor delivery to multiple point of use.

Designed to meet the rigorous demands of semiconductor manufacturing, this system ensures consistent and accurate vapor concentration, supporting various processes such as CVD, ALD or EPI.



Features

- Real-time monitoring of concentration and flow
- Fully automated operation
- State-of-the-art PLC
- Bubbler temperature control
- User-friendly interface